Title (en)

SPUTTERING SURFACE TREATMENT FOR ACTIVE FILTER

Title (de)

SPUTTER-OBERFLÄCHENBEHANDLUNG FÜR AKTIVE FILTER

Title (fr)

TRAITEMENT SURFACIQUE PAR PULVÉRISATION CATHODIQUE POUR FILTRE ACTIF

Publication

EP 4077760 A1 20221026 (FR)

Application

EP 20848804 A 20201217

Priority

- FR 1914764 A 20191218
- FR 2020052502 W 20201217

Abstract (en)

[origin: WO2021123640A1] The invention relates to a method of surface treatment in order to constitute an active filter (21) for a reactive compound of a gas mixture, the method comprising a step of depositing at least one layer of an absorbing material on the surface of a support, the deposition step being carried out by sputtering of an electrode (7) comprising at least one absorbing material chosen to react with the reactive compound of the gas mixture.

IPC 8 full level

C23C 14/56 (2006.01); **B22F 3/105** (2006.01); **B29C 64/00** (2017.01); **B33Y 30/00** (2015.01); **C23C 14/16** (2006.01); **H01J 37/32** (2006.01)

CPC (source: EP)

B22F 10/77 (2021.01); **B33Y 30/00** (2014.12); **C23C 14/165** (2013.01); **C23C 14/564** (2013.01); **H01J 37/32568** (2013.01); **H01J 37/32871** (2013.01); **H01J 37/34** (2013.01); B22F 10/28 (2021.01); B22F 12/70 (2021.01); Y02P 10/25 (2015.11)

Citation (search report)

See references of WO 2021123640A1

Designated contracting state (EPC)

AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

Designated extension state (EPC)

BA ME

Designated validation state (EPC)

KH MA MD TN

DOCDB simple family (publication)

FR 3105263 A1 20210625; **FR 3105263 B1 20220715**; EP 4077760 A1 20221026; WO 2021123640 A1 20210624

DOCDB simple family (application)

FR 1914764 A 20191218; EP 20848804 A 20201217; FR 2020052502 W 20201217